

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 09/945,137
Priority Filing Date August 30, 2001
Inventor Jerome M. Eldridge
Assignee Micron Technology, Inc.
Priority Group Art Unit 2822
Priority Examiner K. Duong
Attorney's Docket No. MI22-2496
Title: Perovskite-Type Material Forming Methods, Capacitor Dielectric Forming
Methods, and Capacitor Constructions

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 C.F.R. " 1.56, 1.97 AND 1.98

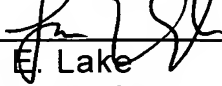
In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 09/945,167, filed August 30, 2001. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 29 Jan 2004

By: 
James E. Lake
Reg. No. 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2496	Priority SERIAL NO. 09/945,137	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Jerome Eldridge		
				Priority FILING DATE August 30, 2001	Priority GROUP 2822	
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,350,738	9/94	Hase et al		
	AB	5,272,341	12/93	Micheli et al		
	AC	5,142,437	08/92	Kammerdiner et al		
	AD	6,461,931	10/02	Eldridge		
	AE	6,025,257	02/00	Jeon, Yoo Chan		
	AF	5,789,268	08/98	Chivukula		
	AG	6,461,931	10/02	Eldridge		
	AH	6,403,441	06/02	Takehiro et al		
	AI	5,953,619	09/99	Miyazawa		
	AJ					
FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes No
	AK	EP 0727832 A1	08/96	EPO/Miyashita et al		
	AL					
	AM					
	AN					
	AP					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
	AP		John Baliga, "New Materials Enhance Memory Performance", Semiconductor International, November 1999, pgs. 1-8.			
	AQ		Advances in Ultrathin Oxides and Oxynitrides I", Materials Research Society Symposium Proceedings Series, Vol. 567,, April 5, 1999, 2 pages.			
	AR		K.S. Tang, W.S. Lau, and G.S. Samudra, "Trends in Dram Dielectrics", IEEE Circuits & Devices, Vol. 13, No. 3, May 1997, pgs. 27-34			
EXAMINER			DATE CONSIDERED			
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>						

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	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AP		D.W. Hess, "Plasma-assisted oxidation, anodization, and nitridation of silicon", IBM Journal of Research & Development, Vol. 43, No. 1/2, Plasma processing, 22 pages.				
	AQ		O. Kubaschewski, E. LL. Evans, "Metallurgical Thermochemistry", Pergamon Press, 1958, pgs. 226-227 and 336-337				
	AR		Ting, Chen, Liu, "Structural evolution and Optical properties of TiO ₂ thin films prepared by thermal oxidation of sputtered Ti films", Journal of Applied Physics, Vol. 88, Number 9, 15 October 2000, pgs.4628-4633.				
EXAMINER				DATE CONSIDERED			
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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2496	Priority SERIAL NO. 09/945,137		
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		Document Number	Date	Country	Class	Subclass	Translation
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	AK						
	AL						
	AM						
	AN						
	AO						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AP		O. Kubaschewski, B.E. Hopkins, "Oxidation of Metals and Alloys", Butterworths, London, Second Edition, 1962, pgs. 36-37 and 70-73.				
	AQ		F.P. Fehlner, "Low-Temperature Oxidation", Monograph published by Electrochemical Society, Pennington, New Jersey, 1983, pgs.31-35.				
	AR		Richard A. Swalin, "Thermodynamics of Solids" Second Edition, Chpt 5, John Wiley & Sons, 1972, pgs. 112-115.				
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